

ABSTRACT**Mask Handling Method, and Mask and Device or Apparatus comprising a Gripper
Therefor, Device Manufacturing Method and Device Manufactured Thereby**

A mask for use in a lithographic projection apparatus comprises three brackets arranged on the circumference of the mask. The brackets are provided with grooves directed to a common imaginary point and are intend to cooperate with three pins provided on a mask gripper present in a mask handling apparatus or device. Preferably, the pins are provided with a rounded top for insertion in associated grooves of the brackets to provide a kinematically-determined mechanical position of the mask on the gripper.

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